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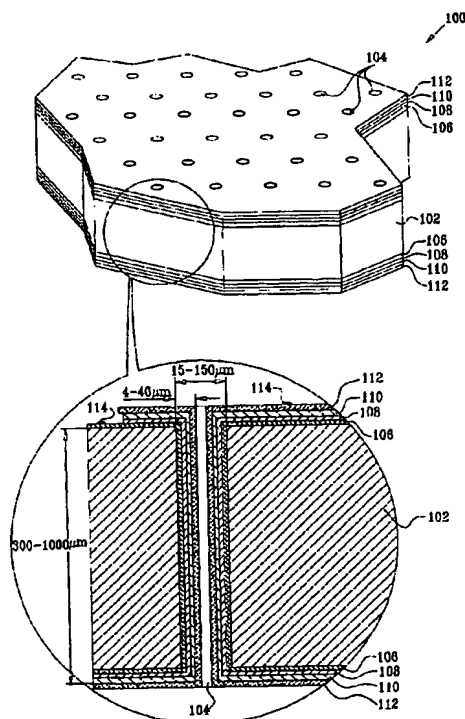
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[Continued on next page]

(54) Title: THIN-FILM CATHODE FOR 3-DIMENSIONAL MICROBATTERY AND METHOD FOR PREPARING SUCH CATHODE



(57) Abstract: A method for producing a microbattery (100) including providing a conductive substrate (102), forming a thin film cathodic layer (108) on at least one surface of the conductive substrate, subsequently forming a thin film electrolyte layer (110) over the cathodic layer and subsequently forming a thin film anodic layer (112) over the electrolyte layer.

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# INTERNATIONAL SEARCH REPORT

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A. CLASSIFICATION OF SUBJECT MATTER  
IPC 7 H01M10/40 H01M4/04 H01M4/02 H01M4/58 C25D9/04

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## B. FIELDS SEARCHED

Minimum documentation searched (classification system followed by classification symbols)  
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Documentation searched other than minimum documentation to the extent that such documents are included in the fields searched

Electronic data base consulted during the International search (name of data base and, where practical, search terms used)

EPO-Internal, WPI Data, PAJ

## C. DOCUMENTS CONSIDERED TO BE RELEVANT

Category *	Citation of document, with indication, where appropriate, of the relevant passages	Relevant to claim No.
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Y	page 2, line 11 - page 3, line 8  claims 9,10	4-6, 13, 16-18, 25, 29-31, 38, 41-43, 50

☒ Further documents are listed in the continuation of box C.

☒ Patent family members are listed in annex.

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C.(Continuation) DOCUMENTS CONSIDERED TO BE RELEVANT		
Category *	Citation of document, with indication, where appropriate, of the relevant passages	Relevant to claim No.
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